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Attorney Declaration No. 033082 M 275

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants : Kazuhide HASEBE, et al. Confirmation No.: 6774
U.S. Serial No. : 10/552,262
Filed : October 5, 2005
Examiner : Lan Vinh
Group Art Unit : 1792
For : SILICON DIOXIDE FILM REMOVING METHOD AND
PROCESSING SYSTEM

AFTER FINAL AMENDMENT UNDER 37 C.F.R. § 1.116

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

MAIL STOP: AF

Sir:

In response the Final Office Action mailed on April 25, 2008, for which the time for response is set to expire July 25, 2008, please amend the above-identified application as set forth below and consider the following remarks.

Amendments to the claims begin on page 2 of this paper.

Remarks begin on page 5 of this paper.